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PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Larry C. Olsen et al.

Application No. 10/726,744

Filed: December 2, 2003

Confirmation No. 6833

For: THERMOELECTRIC DEVICES AND APPLICATIONS FOR THE SAME

Examiner: Not yet assigned

Art Unit: 1753

Attorney Reference No. 23-65037-01

CERTIFICATE OF MAILING

I hereby certify that this paper and the documents referred to as being attached or enclosed herewith are being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: MAIL STOP AMENDMENT, COMMISSIONER FOR PATENTS, P.O. BOX 1450, ALEXANDRIA, VA 22313-1450 on the date shown below.

Attorney
for Applicant(s)

LC 1111

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6/7/04

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PURSUANT TO 37 C.F.R. § 1.97(b)(3)**

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Listed on the accompanying form PTO-1449 and enclosed herewith are several English-language documents. Applicants respectfully request that these documents be listed as references cited on the issued patent.

If the present application was filed after June 30, 2003, copies of United States patents and United States published patent applications do not have to be provided to the Patent Office. This requirement of 37 C.F.R. § 1.98(a)(2)(i) has been waived by the United States Patent and Trademark Office pursuant to the Official Gazette Notice on August 5, 2003 (1276 OG 55). Applicants will provide copies of such patents upon request.

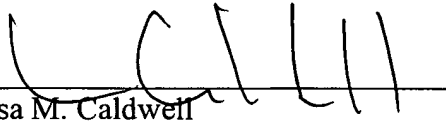
Applicants filed this Information Disclosure Statement ("IDS") before the mailing date of a first Office action on the merits. As a result, no fee should be required to file this IDS. However, if the Patent Office determines that a fee is required for Applicants to file this IDS, please charge any such fees, or credit overpayment, to Deposit Account No. 02-4550. A **duplicate** copy of this Information Disclosure Statement is enclosed.

The filing of this IDS shall not be construed to be an admission that the information cited in the statement is, or is considered to be, prior art or otherwise material to patentability as defined in 37 C.F.R. §1.56.

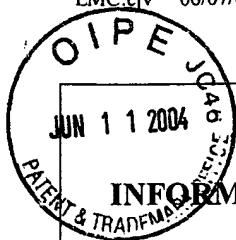
Respectfully submitted,

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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First Named Inventor	Larry C. Olsen
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U.S. PATENT DOCUMENTS

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Examiner's Initials*	Cite No. (optional)	Number	Publication Date	Name of Applicant or Patentee
		6,096,964	8/2000	Ghamaty et al.
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		6,288,321	9/2001	Fleurial et al.
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		6,388,185	5/2002	Fleurial et al.
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FOREIGN PATENT DOCUMENTS

Examiner's Initials*	Cite No. (optional)	Country	Number	Publication Date	Name of Applicant or Patentee

OTHER DOCUMENTS

Examiner's Initials*	Cite No. (optional)	
		Stölzer, M. et al., "Preparation of Highly Effective p-Bi _{2.5} Sb _{1.5} Te ₃ and n-Bi ₂ Te _{2.7} Se _{0.3} Films," 15 th International Conference on Thermoelectrics, pp. 445-449 (1996).
		Stordeur, Matthias et al., "Low Power Thermoelectric Generator - self-sufficient energy supply for micro systems," 16 th International Conference on Thermoelectrics, pp. 575-577 (1997).
		Stark, Ingo et al., "New Micro Thermoelectric Devices Based on Bismuth Telluride-Type Thin Solid Films," 18 th International Conference on Thermoelectrics, pp. 465-472 (1999).
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* Examiner: Initial if reference considered, whether or not in conformance with MPEP 609. Draw line through cite if not in conformance and not considered. Include copy of this form with next communication to applicant.

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		Bergstresser, T.R. et al., "Copper on Polyimide Flexible Substrate for Ultra-Thin, High Performance Applications," 4 pages.	
		Vining, Cronin B., "Semiconductors are cool," <i>Nature</i> , Vol. 413, pp. 577-578 (October 11, 2001).	
		Venkatasubramanian, Rama et al., "Thin-film thermoelectric devices with high room-temperature figures of merit," <i>Nature</i> , Vol. 413, pp. 597-602 (October 11 2001).	
		Chen, G., "Thermal conductivity and ballistic-phonon transport in the cross-plane direction of superlattices," <i>Phys. Rev. B</i> , Vol. 57, No. 23, pp. 14958-14973 (June 15, 1998).	
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		Nolas, G.S. et al., Thermoelectrics, "Basic Principles and New Materials Developments," Springer, Berlin, pp. 111-146 (2001).	
		Tritt, T., "Recent Trends in Thermoelectric Materials Research III," Academic Press, London, Vol. 7, pp. 50-55 (2001).	
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		D.T.S. GmbH: Thin Film Thermoelectric Generators, D.T.S., www.dts-generator.com/index.htm (Printed 5/4/04).	
		D.T.S. GmbH: Thin Film Thermoelectric Generators, Low Power Thermoelectric Generators; www.dts-generator.com/gen.tx.e.htm (Printed 5/4/04).	
		D.T.S. GmbH: Thin Film Thermoelectric Generators, Infrared-Sensors, www.dts-generator.com/sen.tx.e.htm (Printed 5/4/04).	
		D.T.S. GmbH: Thin Film Thermoelectric Generators, Research and development, www.dts-generator.com/dev.tx.e.htm (Printed 5/4/04).	

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